Keisuke Yamamoto

List of Publications by Year in descending order

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840776 794594 31 360 11 19 citations h-index g-index papers 32 32 32 285 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Ohmic contact formation on n-type Ge by direct deposition of TiN. Applied Physics Letters, 2011, 98, .	3.3	44
2	Electrical properties of pseudo-single-crystalline germanium thin-film-transistors fabricated on glass substrates. Applied Physics Letters, $2015,107,100$	3.3	44
3	Two-step synthesis and characterization of vertically stacked SnS–WS ₂ and SnS–MoS ₂ p–n heterojunctions. Physical Chemistry Chemical Physics, 2018, 20, 889-897.	2.8	28
4	Polycrystalline thin-film transistors fabricated on high-mobility solid-phase-crystallized Ge on glass. Applied Physics Letters, 2019, 114, .	3.3	28
5	Isothermal Growth and Stacking Evolution in Highly Uniform Bernal-Stacked Bilayer Graphene. ACS Nano, 2020, 14, 6834-6844.	14.6	28
6	Dramatic enhancement of low electric-field hole mobility in metal source/drain Ge p-channel metal-oxide-semiconductor field-effect transistors by introduction of Al and Hf into SiO2/GeO2 gate stack. Applied Physics Letters, 2013, 103, .	3.3	26
7	Electrical properties of pseudo-single-crystalline Ge films grown by Au-induced layer exchange crystallization at 250 °C. Journal of Applied Physics, 2018, 123, 215704.	2.5	24
8	High-Performance Ge Metal–Oxide–Semiconductor Field-Effect Transistors with a Gate Stack Fabricated by Ultrathin SiO ₂ /GeO ₂ Bilayer Passivation. Applied Physics Express, 2011, 4, 051301.	2.4	23
9	Postmetallization annealing effect of TiN-gate Ge metal-oxide-semiconductor capacitor with ultrathin SiO2/GeO2 bilayer passivation. Applied Physics Letters, 2011, 98, 252102.	3.3	19
10	An accurate characterization of interface-state by deep-level transient spectroscopy for Ge metal-insulator-semiconductor capacitors with SiO2/GeO2 bilayer passivation. Journal of Applied Physics, 2012, 112, 083707.	2.5	16
11	Electrical and structural properties of group-4 transition-metal nitride (TiN, ZrN, and HfN) contacts on Ge. Journal of Applied Physics, 2015, 118, .	2.5	16
12	Fabrication of PtGe/Ge contacts with high on/off ratio and its application to metal source/drain Ge p-channel MOSFETs. Japanese Journal of Applied Physics, 2015, 54, 070306.	1.5	10
13	Expression of Prophenoloxidase mRNA during Silkworm Hemocyte Development. Bioscience, Biotechnology and Biochemistry, 2000, 64, 1197-1202.	1.3	9
14	Border trap evaluation for SiO2/GeO2/Ge gate stacks using deep-level transient spectroscopy. Journal of Applied Physics, 2018, 124, .	2.5	8
15	Sn Concentration Effects on Polycrystalline GeSn Thin Film Transistors. IEEE Electron Device Letters, 2021, 42, 1735-1738.	3.9	8
16	Thermodynamic evaluation of solidification structure of high chromium white cast iron. International Journal of Cast Metals Research, 2003, 16, 435-440.	1.0	5
17	Achievement of low parasitic resistance in Ge n-channel metal-oxide-semiconductor field-effect transistor using an embedded TiN-source/drain structure. Semiconductor Science and Technology, 2017, 32, 035001.	2.0	5
18	Mechanism of mobility enhancement in Ge p-channel metal-oxide-semiconductor field-effect transistor due to introduction of Al atoms into SiO 2 /GeO 2 gate stack. Materials Science in Semiconductor Processing, 2017, 70, 246-253.	4.0	4

#	Article	IF	CITATIONS
19	Fabrication of asymmetric Ge Schottky tunneling source n-channel field-effect transistor and its characterization of tunneling conduction. Materials Science in Semiconductor Processing, 2017, 70, 283-287.	4.0	4
20	Interface trap and border trap characterization for Al2O3/GeOx/Ge gate stacks and influence of these traps on mobility of Ge p-MOSFET. AIP Advances, 2020, 10, 065119.	1.3	3
21	A neural network prediction for the graphite nucleation and morphology in modified cast irons. International Journal of Cast Metals Research, 2001, 14, 157-164.	1.0	2
22	Underlayer Selection to Improve the Performance of Polycrystalline Ge Thin Film Transistors. ECS Transactions, 2020, 98, 423-427.	0.5	2
23	Wide range control of Schottky barrier heights at metal/Ge interfaces with nitrogen-contained amorphous interlayers formed during ZrN sputter deposition. Semiconductor Science and Technology, 2018, 33, 114011.	2.0	1
24	Fabrication and characterization of asymmetric metal/Ge/metal diodes with Ge-on-insulator substrate. Japanese Journal of Applied Physics, 2019, 58, SBBE05.	1.5	1
25	Ge field-effect transistor with asymmetric metal source/drain fabricated on Ge-on-Insulator: Schottky tunneling source mode operation and conventional mode operation. Japanese Journal of Applied Physics, 2019, 58, SBBA14.	1.5	0
26	SiN used as a Stressor in Germanium-On-Insulator Substrate. , 2019, , .		0
27	The Benefits of Using SiN as a Buried Oxide in Germanium-On-Insulator Substrate. , 2020, , .		0
28	(Invited) Border-Trap Characterization for Ge Gate Stacks with Thin GeOX layer Using Deep-Level Transient Spectroscopy. ECS Transactions, 2020, 98, 395-404.	0.5	0
29	Sn Doping Effects in Solid-Phase Crystallized Ge Thin-Film Transistors. ECS Meeting Abstracts, 2020, MA2020-02, 1353-1353.	0.0	0
30	Underlayer Selection to Improve the Performance of Polycrystalline Ge Thin Film Transistors. ECS Meeting Abstracts, 2020, MA2020-02, 1759-1759.	0.0	0
31	(Invited) Border-Trap Characterization for Ge Gate Stacks with Thin GeO _X layer Using Deep-Level Transient Spectroscopy. ECS Meeting Abstracts, 2020, MA2020-02, 1754-1754.	0.0	O